Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the present application.

Listing of Claims:

Claim 1 (currently amended): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

coated to a given thickness in at least a single layer over said cemented-carbide base material, a compound thin film made up of a combination of, in given elemental proportions, one or more elements selected from the group titanium, chromium, vanadium, silicon and aluminum, and one or more elements selected from carbon and nitrogen; wherein

~~said compound thin film is coated in at least a single layer~~

said compound thin film is vapor-deposited onto said base material under reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions that, together with said given thickness and said given elemental proportions, are predetermined so as to impart a compressive residual stress of 0.1 GPa or more and 8 GPa or less to said compound thin film.

Claim 2 (currently amended): The surface-coated machining tool set forth in claim 1, wherein said predetermined thickness of said compound thin film is 0.05 μm or more and 3 μm or less ~~in thickness~~.

Claim 3 (canceled)

Claim 4 (original): The surface-coated machining tool set forth in claim 1, wherein said compound thin film is in surface roughness adjusted to be 0.01 μm or more and 0.5 μm or less by indication Ra.

Claim 5 (currently amended): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

a hard carbon thin film made up essentially of carbon atoms only, coated to a given thickness over said cemented-carbide base material in at least a single layer, by a physical vapor deposition method in which graphite is made a raw material, and under reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions that, together with said given thickness, are predetermined so as to impart a compressive residual stress of 0.1 GPa or more and 8 GPa or less to said compound thin film; ~~wherein~~

~~said hard carbon thin film is coated in at least a single layer~~.

Claim 6 (original): The surface-coated machining tool set forth in claim 5, wherein said hard carbon thin film is 0.05 μm or more, and 3 μm or less in thickness.

Claim 7 (canceled)

Claim 8 (previously presented): The surface-coated machining tool set forth in claim 5, wherein said hard carbon thin film is in surface roughness adjusted to be 0.01 μm or more and 0.5 μm or less by indication Ra.

Claim 9 (original): The surface-coated machining tool set forth in claim 1, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 10 (original): The surface-coated machining tool set forth in claim 2, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 11 (original): The surface-coated machining tool set forth in claim 3, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 12 (original): The surface-coated machining tool set forth in claim 4, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 13 (original): The surface-coated machining tool set forth in claim 5, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal grain size.

Claim 14 (original): The surface-coated machining tool set forth in claim 6, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 15 (original): The surface-coated machining tool set forth in claim 7, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 16 (original): The surface-coated machining tool set forth in claim 8, wherein the tungsten carbide in said cemented-carbide base material is 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size.

Claim 17 (previously presented): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

coated to a given thickness in at least a single layer over said cemented-carbide base material, by a ~~physical-vapor~~ cathodic-arc deposition method, a compound thin film made up of a combination of, in given elemental proportions, one or more elements selected from the group titanium, chromium, vanadium, silicon and aluminum, and one or more elements selected from carbon and nitrogen; wherein

~~said compound thin film is coated in at least a single layer; and~~

reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions in said cathodic-arc deposition method, together with said given thickness and said given elemental proportions, are predetermined so as to impart a compressive residual stress of 0.1 GPa or more and 8 GPa or less ~~is imparted~~ to said compound thin film.

Claim 18 (previously presented): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

coated in at least a single layer over said cemented carbide base material, by a ~~physical-vapor~~ cathodic-arc deposition method, a compound thin film 0.05 μm or more and 3 μm or less in thickness, made up of a combination of, in given elemental proportions, one or more elements selected from the group titanium, chromium, vanadium, silicon and aluminum, and one or more elements selected from carbon and nitrogen; wherein

~~said compound thin film is coated in at least a single layer; and~~ reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions in said cathodic-arc deposition method, together with said thickness and said given elemental proportions, are predetermined so as to impart a compressive residual stress of 0.1 GPa or more and 8 GPa or less ~~is imparted~~ to said compound thin film

Claim 19 (previously presented): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size, and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

a hard carbon thin film made up essentially of carbon atoms only, coated to 0.05 μm or more, and 3 μm or less in thickness over said cemented-carbide base material in at least a single layer, by a physical vapor deposition method in which graphite is made a raw material, and under reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions that, together with said thickness, are predetermined so as to impart a compressive residual stress of 0.1 GPa or more and 8 GPa or less to said compound thin film; ~~wherein said hard carbon thin film is coated in at least a single layer~~.

Claim 20 (previously presented): A surface-coated machining tool, comprising:

a cemented-carbide base material containing tungsten carbide 0.1 μm or more and 1.5 μm or less in pre-sintering crystal-grain size, and cobalt, with the cobalt inclusion amount being 4 weight % or more and 12 weight % or less; and

a hard carbon thin film made up essentially of carbon atoms only, coated to a given thickness over said cemented-carbide base material in at least a single layer, by a ~~physical vapor~~ cathodic-arc deposition method in which graphite is made a raw

material, and under reaction-gas pressure, base-material bias voltage, and deposition-temperature conditions that, together with said given thickness, are predetermined so as to impart; ~~wherein~~

~~said hard carbon thin film is coated in at least a single layer; and~~

a compressive residual stress of 0.1 GPa or more and 8 GPa or less is imparted to said hard carbon thin film.